



In the United States Patent and Trademark Office

Inventor: Aratani et al.

Examiner: R. McDonald #
21/100

Serial No.: 09/429,719

Group Unit: 1753

Title: Thin Film Formation Use ...

Atty. Docket No. 9792486-0100

Response "E" to Final Office Action After RCE Filing

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In response to the Final Office Action dated 26 April 2002, the applicants respond as follows.

A. In the Claims, please amend as follows:

17. (amended) A method of forming a thin film comprising the step of: forming an AgPd alloy thin film using a sputtering target material, the AgPd alloy thin film comprising Pd in an amount ranging from 0.5 to 4.9 atomic % and Cu in an amount ranging from 0.1 to 3.5 atomic %; and irradiating an information recording layer with a light beam having a wavelength less than or equal to 650 nm.

18. The method of claim 17, wherein the thin film has a thickness from approximately 500 Angstroms to approximately 1500 Angstroms.

19. Canceled.

20. The method of claim 17, wherein the thin film has a thickness from approximately 500 Angstroms to approximately 1500 Angstroms; and wherein the wavelength is less than or equal to 650 nm.

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